



XA-9387  
PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Hitoshi TAKEUCHI

Appln. No.: 09/714,183

Group Art Unit: 2877

Filed: November 17, 2000

Examiner: R. Punnoose

For: ABERRATION MEASURING APPARATUS, ABERRATION MEASURING  
METHOD, PROJECTION EXPOSURE APPARATUS HAVING THE SAME  
MEASURING APPARATUS, DEVICE MANUFACTURING METHOD USING  
THE SAME MEASURING METHOD, AND EXPOSURE METHOD

Allowed: December 15, 2003

Confirmation No.: 5906

\* \* \*

FIFTH SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner of Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

ATTN: Mail Stop RCE

Sir:

Supplementing the Information Disclosure Statement  
dated August 6, 2003, and without any assertion as to  
materiality or prior art effect, the documents listed on  
the attached Form PTO-1449 are hereby cited.

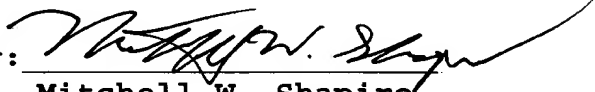
The Commissioner is hereby authorized to charge to Deposit Account No. 50-1165 any fees under 37 C.F.R. §§ 1.16 and 1.17 that may be required by this paper and to credit any overpayment to that Account. If any extension of time is required in connection with the filing of this paper and has not been requested separately, such extension is hereby requested.

Respectfully submitted,

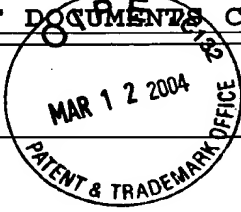
MWS:lat

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By:

  
Mitchell W. Shapiro  
Reg. No. 31,568

March 12, 2004

FORM PTO-1449				Atty. Docket No. <b>XA-9387</b>		Appln. No. <b>09/714,183</b>	
<b>LIST OF DOCUMENTS CITED BY APPLICANT</b>				Applicant <b>Hitoshi TAKEUCHI</b>			
				Filing Date <b>November 17, 2000</b>		Group <b>2877</b>	
				<b>U.S. PATENT DOCUMENTS</b>			
Examiner Initial		Document Number	Date	Name	Class	Sub-class	Filing Date
	AA	4,141,652	2/27/79	Feinleib	356	121	
	AB	4,326,800	4/27/82	Fitts	356	152	
	AC	4,518,854	5/21/85	Hutchin	250	201	
	AD	4,666,298	5/19/87	Protz	356	121	
	AE	5,362,956	11/8/94	Anafi et al.	250	201.9	
	AF	5,760,879	6/2/98	Shinonaga et al.	355	55	
	AG	5,898,501	4/27/99	Suzuki et al.	356	359	
	AH	5,978,085	11/2/99	Smith et al.	356	354	
	AI	6,278,514	8/21/01	Ohsaki	355	55	
	AJ	6,360,012	3/19/02	Kreuzer	382	211	
	AK	5,828,455	10/27/98	Smith et al.	356	354	
<b>FOREIGN PATENT DOCUMENTS</b>							
Examiner Initial		Document Number	Date	Country	Class	Sub-class	Translation
	AL	WO99/66308	12/23/99	WIPO			
	AM						
	AN						
	AO						
	AP						
	AQ						
<b>OTHER (including author, title, date, pertinent pages, etc.)</b>							
	AR	Freitag et al., "Wavefront analysis of photolithographic lenses," JR, 1/1991, pp. VIII-XII.					
	AS	Noguchi et al. "Shack-Hartmann Wave-Front Analyzer to Measure F/5 Mirrors," Active Optic Experiments. I., 1989, Publ. Natl. Astron, Obs. Japan, Vol. 1, 49-55.					
Examiner				Date Considered			
<b>EXAMINER:</b> Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.							